nSpec® LS Optical Inspection System

nanotronics

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Whatever the user's specific sample inspection requirements, Nanotronics provides a wide range of solutions for obtaining rapid results.

nSpec® LS is the ideal system for R&D and process development. It runs multiple scans sequentially. User-friendly software makes configuring recipes next to effortless. And, as needs evolve, recipes are easy to save and modify.

Semi automated inspection for:
· Substrate, epi, and patterned wafers
· Transparent and opaque materials
· Die on film tape, trays, gel-pak or waffle packs
· Photomasks
· Sample fragments

Features:
· Multiple resolution settings, ranging from 0.25 µm and greater
· Rapid scanning
· Customizable defect reports
· Variety of sample chucks to meet specific needs
· Robust analysis for defect or feature of interest detection and classification
· Inspection and review procedures
· Multi-system synchronization
· Small footprint and minimal facilities requirements
· Rack mount controls
. Field upgradeable to nSpec® PS system

SYSTEM
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Weight	240 kg
Dimensions (W x D x H)	165cm x 157cm x 194cm
Min. Vacuum Requirement	-21 in. Hg (-70 kPa)
Power Supply (UPS included)	120VAC, 30A, 50-60Hz / 208VAC, 15A, 50-60Hz

OPTICS
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Illumination Modes	Brightfield, Darkfield, DIC (Nomarski)
Light Source	White light LED (other options available)
Objectives	5x included, 1.25, 2.5, 10, 20, or 50x, user selectable (5 position turret)

STAGE
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Travel, typical	200 mm X and Y direction
Positioning	Linear servo motors with closed loop encoders (50 nm resolution)
Repeatability	+/- 0.5 µm
Travel Flatness	30 µm
Construction	Precision ground raceways and crossed roller bearings
Mounting Platform	Microscope/heavy duty pedestal integrated into isolation table
Centered Load Capacity	2.27 kg
Weight	11.33 kg
Size (W x D x H)	36 cm x 37 cm x 4 cm stage dimensions

OPTIONS
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AFM	Specs available upon request
SECS/GEM	
Transmitted Light	
Automatic Wafer Handling	